

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Mitsutoshi MIYASAKA

Application No.: Rule 53(b) Divisional of
Application No. 09/400,303

1c971 U.S. PTO
10/099963
03/19/02

Filed: March 19, 2002

Docket No.: 038839.02

For: A METHOD FOR FORMING CRYSTALLINE SEMICONDUCTOR LAYERS, A
METHOD FOR FABRICATING THIN FILM TRANSISTORS, AND A METHOD FOR
FABRICATING SOLAR CELLS AND ACTIVE MATRIX LIQUID CRYSTAL DEVICES

INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. The references were cited by or submitted to the Office in parent application No. 09/400,303, filed September 21, 1999, which is relied upon for an earlier filing date under 35 U.S.C. §120. Thus, copies of these references are not attached. 37 CFR §1.98(d).

Respectfully submitted,

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